


INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Attorney Docket Number	6333-67325
				Application Number	Not yet assigned
				Filing Date	Herewith
				First Named Inventor	Dickey
				Art Unit	Not yet assigned
				Examiner Name	Not yet assigned
U.S. PATENT DOCUMENTS					
Examiner's Initials*	Cite No. (optional)	Number	Date	Name	
✓		4,058,430	11/15/77	Suntola et al.	
		4,389,973	6/28/83	Suntola et al.	
		5,091,320	2/25/92	Aspnes et al.	
		5,257,132	10/26/93	Ceglio et al.	
		5,321,713	6/14/94	Khan et al.	
		5,438,952	8/8/95	Otsuka	
		5,458,084	10/17/95	Thorne et al.	
		5,677,594	10/14/97	Sun et al.	
		5,711,811	1/27/98	Suntola et al.	
		5,712,528	1/27/98	Barrow et al.	
		5,785,756	7/28/98	Lee	
		5,804,919	9/8/98	Jacobsen et al.	
		5,872,655	2/16/99	Seddon et al.	
✓		6,449,403	9/10/02	Cush et al.	

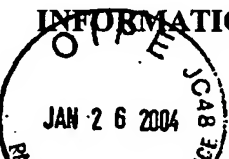
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				Examiner Name	Not yet assigned
FOREIGN PATENT DOCUMENTS					
Examiner's Initials*	Cite No. (optional)	Number	Date	Country	
		JP59045408	3/14/84	Japan	
		JP6196809	7/15/94	Japan	
		JP62002213	1/8/87	Japan	
Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS			
		T. Suntola, "Cost-effective Processing By Atomic Layer Epitaxy," <u>Thin Solid Films</u> , 225:96-98 (1993).			
		T. Suntola, "Atomic Layer Epitaxy," <u>Thin Solid Films</u>, 216:84-89 (1992).			

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT 	Attorney Docket Number	6333-67325
	Application Number	10/713,362
	Filing Date	November 14, 2003
	First Named Inventor	Dickey et al.
	Art Unit	
	Examiner Name	

U.S. PATENT DOCUMENTS


Examiner's Initials*	Cite No. (optional)	Number	Date	Name
M		4,915,476	4-10-90	Hall et al
		5,102,694	4-7-92	Taylor et al.
		5,164,040	11-17-92	Eres et al.
		5,458,084	10-17-95	Thorne et al.
		5,472,505	12-5-95	Lee et al
		5,724,144	3-3-98	Muller et al.
N		5,916,365	6-29-99	Sherman

FOREIGN PATENT PUBLICATION

Examiner's Initials*	Cite No. (optional)	Number	Date	Country
M		0 416 251 A2	3-13-91	European
M		61018124	1-27-86	Japanese Abstract

OTHER DOCUMENTS

Examiner's Initials*	Cite No. (optional)	
M		Kukli et al., "Real-Time Monitoring in Atomic Layer Deposition of TiO ₂ from TiI ₄ and H ₂ O—H ₂ O ₂ " Langmuir 2000, 16: 8122-8128
M		Juppo et al., "In Situ Mass Spectrometry Study on Surface Reactions in Atomic Layer Deposition of Al ₂ O ₃ Thin Films from Trimethylalumin and Water", Langmuir 2000, 16, 4034-4039
M		Aarik et al., "Anomalous effect of temperature on atomic layer deposition of titanium dioxide", Journal of Crystal Growth 220 (2000) 531-537

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